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Filing Date	July 27, 2001					
First Named Inventor	Chin, et al.					
Art Unit	2125					
Examiner Name	Not yet assigned					
Attorney Docket Number	5017/ISM/CORE/ MCVD/SB					

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Sheet | of 2

April Lion Number	09/917,842
Filing Date	July 27, 2001
First Named Inventor	Chin, et al.
Group Art Unit	2125
Examiner Name	Kosowski
Attorney Docket Number	5017/ISM/CORE/MCVD
Submission Date	: 7

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